

Figures

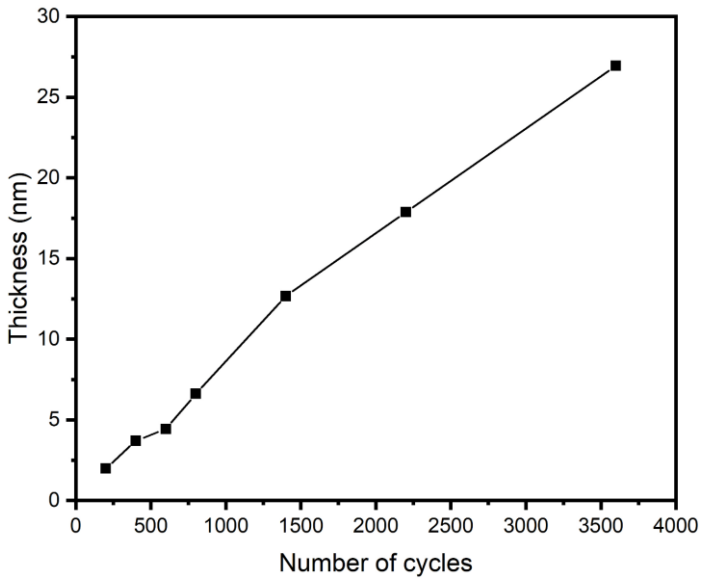


Figure 1 – Film thickness as function of cycles. Films deposited at 200°C

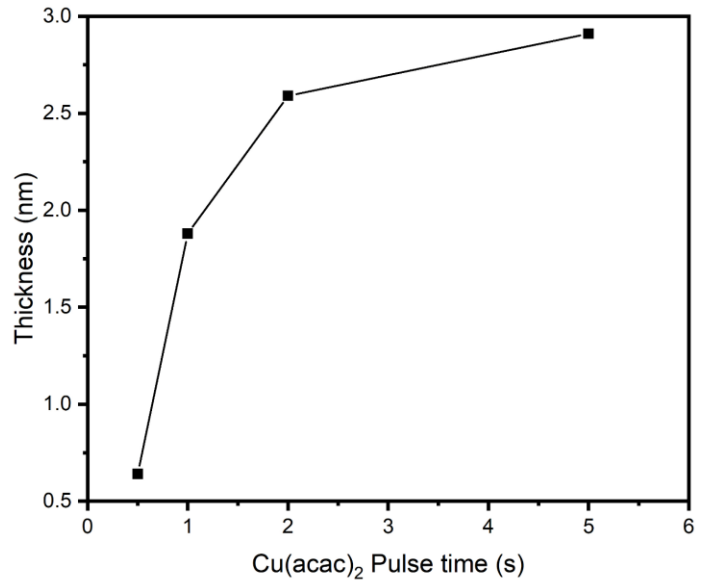


Figure 2 – Film thickness as function of Cu(acac)₂ pulse time. Films deposited at 200°C.

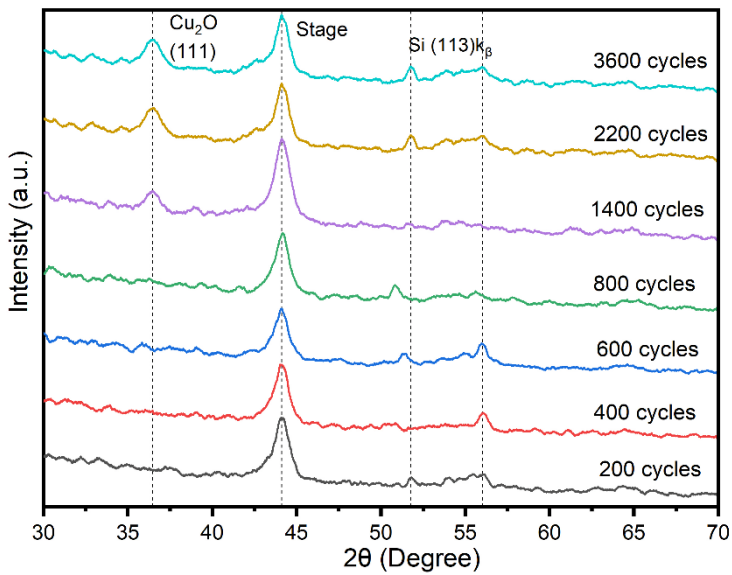


Figure 3 – GIXRD of films deposited at 200°C using Cu(acac)₂ and H₂O/O₂.

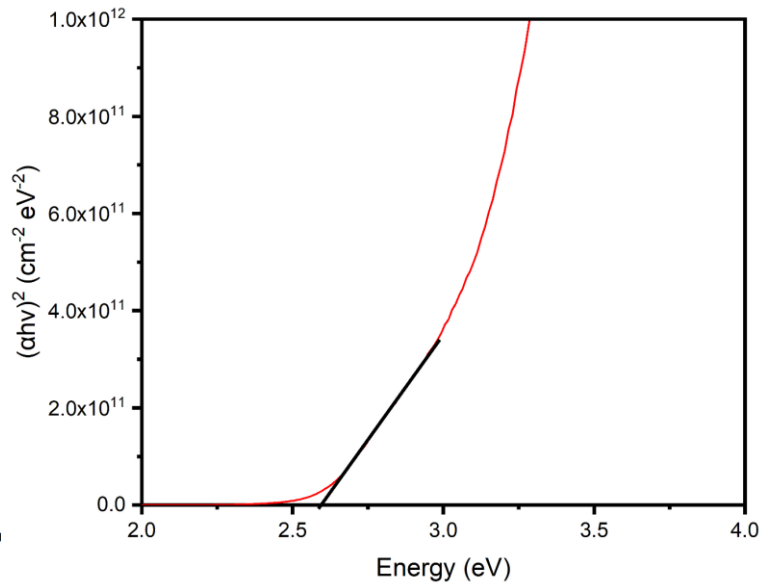


Figure 4 – Tauc plot of Cu₂O film prepared by ALD at 200°C with 3600 cycles.